

Optosky(Xiamen)Photonics Inc. E-mail: support@optosky.com Tel: +86-592-6102588 Web: www.optosky.net

Optical Film Thickness Gauge

SM200

Feature

- Non-contact, non-destructive testing system;
- Ultra-long life light source, higher luminous efficiency;
- High-resolution, high-sensitivity spectrometer, the measurement results are more accurate and reliable;
- The software interface is intuitive, and the operation is convenient and time-saving;
- Historical data storage to help users better grasp the results;
- Desktop distribution design, suitable for rich scenarios;
- Low maintenance cost and convenient maintenance;

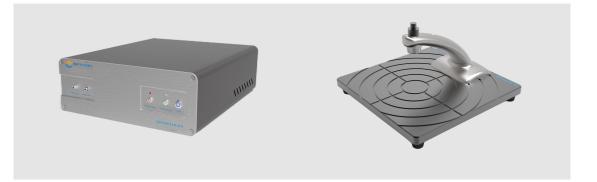
Description

SM200 is an automatic thin film thickness mapper developed by utilizing the principle of thin film reflected light interference. It uses the light with the widest wavelength range of 200-1700nm to vertically incident on the surface of the film. As long as the film has a certain degree of transmission, the SM200 can calculate the thickness of the film according to the reflected interference spectrum, as well as other optical constants such as reflectivity. , refractive index and extinction coefficient, etc., the thickness of the maximum mapping range can reach $1nm \sim 250um$.

The SM200 automatic optical film thickness mapper is constructed by the surveying and mapping host, the surveying and mapping platform, the Y-type optical fiber and the host computer software. The leading generation of automated optical film thickness gauges.

Application

- Semiconductor coating: photoresist, oxide, desalination layer, silicon-on-insulator, wafer back grinding;
- Liquid crystal display: gap thickness, polyimide, ITO transparent conductive film;
- Optical coating: hard coating, anti-reflection layer;
- Microelectronic system: photoresist, silicon film, printed circuit board;
- Biomedical: medical equipment, Parylene

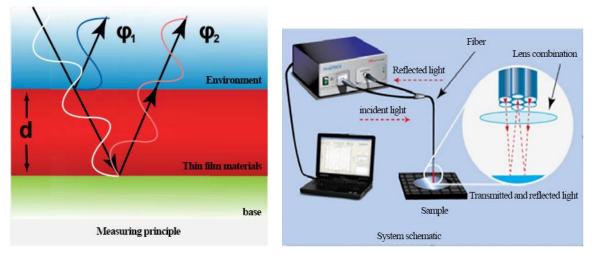


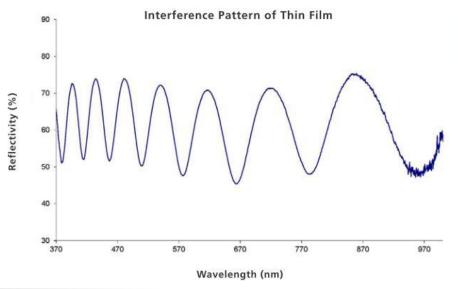


1. Work Principle

When the incident light penetrates the interface of different materials, part of the light will be reflected. Due to the fluctuation of light, the reflected light from multiple interfaces interferes with each other, so that the multi-wavelength spectrum of the reflected light oscillates. From the oscillation frequency of the spectrum, we can judge the distance of different interfaces and then obtain the thickness of the material (more oscillations represent a larger thickness), and other material properties such as refractive index and roughness can also be measured at the same time, as shown in the left figure below.

Optosky fully absorbed the pain points of the industry, dug deep into the needs of customers, and devoted itself to building the leading automatic film thickness measuring instrument in China - SM200, which emits light from the host light source and irradiates the surface of the sample to be measured through the Y-type optical fiber. The Y-type fiber is composed of 7 thin fibers to form a plum blossom, the outer 6 fibers emit light, and the middle fiber guides the reflected interference light back to the spectrometer inside the host for measurement and calculation. The principle of SM200 system is shown in the figure below right.







2. Parameters

		SM200-ł	HUV				
		SM200-LUV	'				
			SM200				
	SM200-NIR						
Inm	l 10nm	100nm	l 1μm	Ι 10μm	Ι 100μm	l 1mm	
Model	SM2	00-LUV	SM200-HUV	SM200		SM200-NIR	
General specific	ations						
Spectral range	20	0nm-1000nm	200nm-1000nm	400nm-1000i	nm	900nm-1700nm	
Light source		Deuterium halogen Lamp			Tungsten halogen lamp		
Measurement sp	ecifications	,					
Thickness range ¹		1nm-10um	1nm~30um	20nm-60un	n	100nm-250um	
Accuracy ²		±2nm 或 0.2%			±3nm 或 0.4%		
Incidence angle		90°					
Film thickness la	/ers		1~	~3			
Sample material		Transparent or translucent film					
Measurement mo	de	Single-point/multi-point/automated measurements					
Spot size ³		2mm					
Sample size			Diameters from 1mm	n to 300mm or la	rger		
Basic requireme	nts						
Operating system		Windows10/11					
Indicator light	D	euterium lamp ind indi	Halogen lamp indication				
Button	Powe	Power buttons, deuterium lamps, halogen lamps Power button, hal				logen power	
External interface		Power outlet, USB 2.0, RJ45					
Scanning platform	n	Rotate + X axis movement					
Movable stroke		150mm*360°					
Material		Aluminum alloy					
Power supply		100~240VAC					
Packing list	1	Mainframe, measuring platform, power cord, communication cable, optical probe, Y-				cal probe, Y-fiber	
Remarks:1. Depends on th2. The larger one		r and depends on t	he material;				